TEMPERATURE MEASUREMENT ASSEMBLY, SUBSTRATE PROCESSING APPARATUS, METHOD OF PROCESSING SUBSTRATE, METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, AND PROGRAM

ABSTRACT

There is provided a technique that includes: (a) an insulating tube with two through-holes through which two conductive wires of a temperature sensor are respectively inserted; (b) a first protective tube, through which the insulating tube is inserted inwardly from a first end of the first protective tube; (c) a cylindrical sleeve airtightly connected to the first end of the first protective tube and airtightly installed to an installation port from an outside of a furnace; and (d) a second protective tube mounted to the installation port from an inside of the furnace and covering the entire first protective tube on the inside of the furnace.

Fig. 2